

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Toshirou Kisakibaru, Shigeru Kouchiyama, Makoto Okada, and Kouta Ueno

Application No.: 10/537,133

Group No.: 2823

Filed: 02/27/2003

Examiner: Coleman, W.

For: Air-curtain Forming Apparatus for Wafer Hermetic Container in Semiconductor-Fabrication Equipment of Minienvironment System (as amended)

Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT TRANSMITTAL

1. Transmitted herewith is an amendment for this application.

STATUS

2. Applicant is other than a small entity.

EXTENSION OF TERM

3. The proceedings herein are for a patent application and the provisions of 37 C.F.R. 1.136 apply. Applicant petitions for an extension of time under 37 C.F.R. 1.136 (fees: 37 C.F.R. 1.17(a)(1)-(4)) for two months:

Fee: \$460.00

FEE FOR CLAIMS

4. The fee for claims (37 C.F.R. 1.16(b)-(d)) has been calculated as shown below:

	(Col. 1)	(Col. 2)	(Col. 3)	OTHER THAN A SMALL ENTITY			
	CLAIMS						
	REMAINING	HIGHEST NO.	PRESENT			ADDIT.	
	AFTER	PREVIOUSLY	EXTRA	RATE		FEE	
	AMENDMENT	PAID FOR					
TOTAL	7	— 20	= 0	x \$	50.00	= \$	0.00
INDEP.	3	— 3	= 0	x \$	210.00	= \$	0.00
FIRST PRESENTATION OF MULTIPLE DEP. CLAIM				+	\$		0.00
TOTAL							
ADDIT. FEE						\$	0.00

No additional fee for claims is required.

FEE PAYMENT

5. Authorization is hereby made to charge the amount of \$460.00 to Deposit Account No. 19-4972.

Charge any additional fees required by this paper or credit any overpayment in the manner authorized above.

FEE DEFICIENCY

6. If an additional extension and/or fee is required, charge Account No. 19-4972.
If an additional fee for claims is required, charge Account No. 19-4972.

Date: February 14, 2008

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshirou Kisakibaru

Attorney Docket: 2471/112

App. No.: 10/537,133

Art Unit: 2823

Filing Date: June 2, 2005

Examiner: William D. Coleman

For: Air-curtain Forming Apparatus for Wafer Hermetic Container in Semiconductor-Fabrication Equipment of Minienvironment System *(as amended)*

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office action dated October 2, 2007, Applicants respond as follows:

Amendments to the Specification appear on page 2 of this paper.

Amendments to the Claims are reflected in the **Listing of Claims** which begins on page 3 of this paper.

Remarks begin on page 6 of this paper.